US 20230230799A1

(19) **United States**

(12) **Patent Application Publication** (10) **Pub. No.: US 2023/0230799 A1**

IMAI et al. (43) **Pub. Date: Jul. 20, 2023**

(54) **SAMPLE IMAGE OBSERVATION DEVICE AND METHOD FOR SAME**

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(21) Appl. No.: **17/928,691**

(22) PCT Filed: **Jul. 14, 2020**

(86) PCT No.: **PCT/JP2020/027381**

§ 371 (c)(1),
(2) Date: **Nov. 30, 2022**

Publication Classification

(51) **Int. Cl.**

H01J 37/22	(2006.01)
H01J 37/28	(2006.01)
H01J 37/26	(2006.01)

(52) **U.S. Cl.**

CPC ***H01J 37/222*** (2013.01); ***H01J 37/28*** (2013.01); ***H01J 37/265*** (2013.01); *H01J 2237/226* (2013.01); *H01J 2237/24578* (2013.01)

(57) **ABSTRACT**

Provided is a sample image observation device including an SEM and a control system configured to control the SEM. An observation region of a sample is divided into a plurality of sections, and restoration processing is performed on an image which is acquired by irradiating each section with a sparse electron beam, based on scanning characteristics in the section. A reduction in quality of a restored image due to a beam irradiation position deviation caused by a scanning response is prevented and restoration with high accuracy and high throughput under a condition for preventing sample damage is possible.